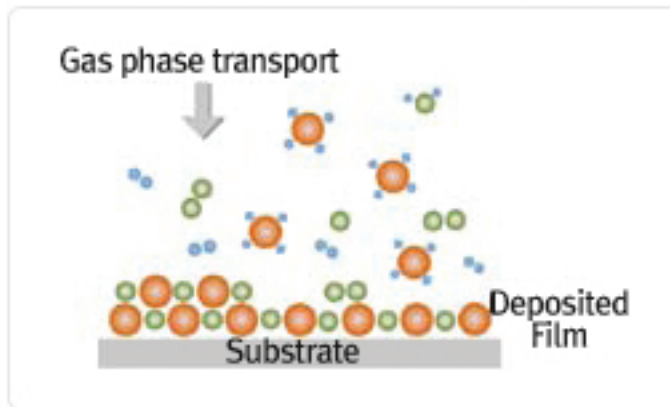


Max deposition space	Custom-made
Operating gases	mass flow control system Ar, O ₂ , C ₂ H ₂ , CH ₄ , C ₆ H ₆ , ETC.
Initial vacuum	~10 ⁻⁶ torr
Bias power	0~R.F
Device operation	Full automatic/half automatic
Cooling method	water cooled

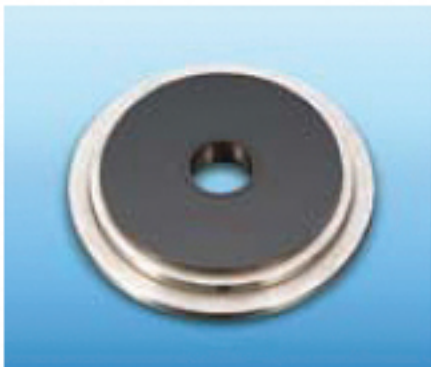
Layer deposition of a PECVD system



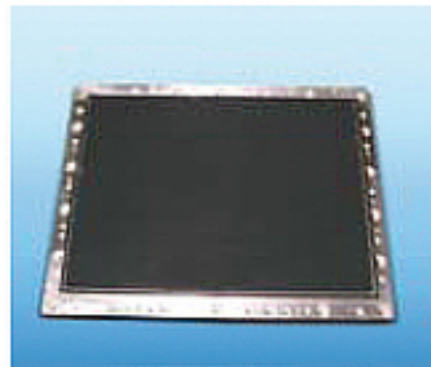
PECVD system's advantages

- Highly pure film formed
- Regular quality over a large area
- High deposition rate
- Easy process control, Mass quantity handling.
- Low temperature for layer deposition

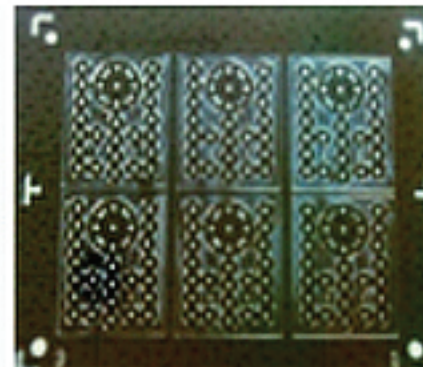
Application- hard surface coating



CD molds



LCD molds



Mobile phone key pad molds